

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Kazutaka Yanagita et al.

Group Art Unit: to be assigned

Serial No.: to be assigned

Examiner: to be assigned

Filed: August 13, 2003

For: SAMPLE PROCESSING SYSTEM

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This Information Disclosure Statement is filed in accordance with 37 C.F.R. §§1.56, 1.97 and 1.98. The items listed on Form PTO-1449, a copy of which is not enclosed, are made of record to assist the Patent and Trademark Office in its examination of this application. The Examiner is respectfully requested to fully consider the items and to independently ascertain their teaching.

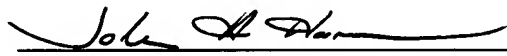
1. ☐ For each of the following items listed on the enclosed copy of Form PTO-1449 that is not in the English language, an English language translation of that item or a portion thereof or a concise explanation of the relevance of that item is enclosed:
2. ☐ For each of the following items listed on the enclosed copy of Form PTO-1449 that is not in the English language, a concise explanation of the relevance of that item is incorporated in the specification of the above-identified application.
3. ☒ Any copy of the items listed on the enclosed copy of Form PTO-1449 that is not enclosed with this Information Disclosure Statement was previously cited by or submitted to the Patent and Trademark Office in application Serial No. 10/153,608, filed May 24, 2002.

PATENT
Attorney's Docket No. 1232-4590US2

4. ☒ No fee is due under 37 C.F.R. §1.17(p) for this Information Disclosure Statement since it is being filed in compliance with:
- ☒ 37 C.F.R. §1.97(b)(1), within three months of the filing date of a national application other than a CPA; or
 - ☐ 37 C.F.R. §1.97(b)(2), within three months of the date of entry into the national stage as set forth in §1.491 in an international application; or
 - ☒ 37 C.F.R. §1.97(b)(3), before the mailing date of a first Office action on the merits; or
 - ☐ 37 C.F.R. §1.97(b)(4) before the mailing date of a first office action after the filing of an RCE under §1.114.
- ☒ The Commissioner is hereby authorized to charge any additional fees which may be required for this Information Disclosure Statement, or credit any overpayment to Deposit Account No. 13-4503, Order No. 1232-4590US2.

Respectfully submitted,
MORGAN & FINNEGAN, L.L.P.

Dated: August 13, 2003

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FORM PTO-1449 INFORMATION DISCLOSURE CITATION				Attorney Docket: 1232-4590US2		Serial No.: to be assigned	
				Applicants: Yanagita et al.		Examiner: to be assigned	
				Filing Date: August 13, 2003		Group Art Unit: to be assigned	
U.S. PATENT DOCUMENTS							
Examiner Initial		Patent Number	Publication Date	Name	Class	Sub-Class	Filing Date
	AA	3,493,155	02/03/70	Irving Litant et al.	225	2	
	AB	3,549,446	12/22/70	R.W. Bennett et al.	156	230	
	AC	3,667,661	06/06/72	Farmer	225	2	
	AD	3,730,410	05/01/73	Altshuler	225	96.5	
	AE	4,962,879	10/16/90	Goesele et al.	156	281X	
	AF	5,100,544	03/31/92	Izutani, et al.	210	75	
	AG	5,255,853	10/26/93	Munoz	83	177X	
	AH	5,374,564	12/20/94	Bruehl	437	24	
	AI	5,379,235	01/03/95	Fisher et al.	364	508	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Patent Number	Publication Date	Country	Class	Sub-Class	Translation
	AJ	KR 1998-33377	0/75/98	Korean			<input type="checkbox"/> Yes <input type="checkbox"/> No
	AK	EP 0 709 876 A1	05/01/96	Europe			<input type="checkbox"/> Yes <input type="checkbox"/> No
	AL	EP 0 840 381 A2	05/06/98	Europe			<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No
	AM	EP 0 843 345 A2	5/20/98	Europe			<input type="checkbox"/> Yes <input type="checkbox"/> No
OTHER DOCUMENTS (Including Author, Title, Date, etc.)							
	AN	"Single-Crystal Silicon on Non-Single-Crystal Insulators", G.W. Cullen, <u>Journal of Crystal Growth</u> , Vol. 63, No. 3, pp. 429-590, 1983					
	AO	"Crystalline Quality of Silicon Layer Formed by FIPOS Technology", Kazuo IMAI et al., <u>Journal of Crystal Growth</u> , Vol. 63, pp 547-553, 1987					
	AP	"Silicon-On-Insulator by Wafer Bonding: A Review", W.P. Maszara, <u>Journal of Electrochemical Society</u> , Vol. 138, pp. 341-347, 1991					
Examiner				Date Considered			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP §609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							

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U.S. PATENT DOCUMENTS							
Examiner Initial		Patent Number	Publication Date	Name	Class	Sub-Class	Filing Date
	AQ	5,510,019	4/23/96	Yabumoto et al.	210	137	
	AR	5,747,387	05/05/98	Koizumi et al.	438	906X	
	AS	5,783,022	07/21/98	Cha et al.	156	344	
	AT	5,849,602	12/15/98	Okamura et al.	438	908X	
	AU	5,876,497	03/02/99	Atoji	117	85	
	AV	5,928,389	7/27/99	Jevtic	29	25.01	
	AW	5,934,856	08/10/99	Asakawa et al.	414	217	
	AX	5,994,207	11/30/99	Henley et al.	438	515	02/19/98
	AY	6,122,566	09/19/00	Nguyen et al.	438	908X	03/03/98
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Patent Number	Publication Date	Country	Class	Sub-Class	Translation
	AZ	EP 0 999 578 A2	05/10/00	Europe			<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No
	BA	EP 1 026 729 A2	08/09/00	Europe			<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No
	BB	EP 1 045 448 A1	10/18/00	Europe			<input type="checkbox"/> Yes <input type="checkbox"/> No
	BC	EP 0 926 719 A2	06/30/99	Europe			<input type="checkbox"/> Yes <input type="checkbox"/> No
OTHER DOCUMENTS (Including Author, Title, Date, etc.)							
	BD	"Light Scattering Topography Characterization of Bonded SOI Wafer", H. Baumgart, et al., <u>Extended Abstracts</u> , Vol. 91-2, pp. 733-734, 1991					
	BE	"Thinning of Bonded Wafer: Etch-Stop Approaches", Charges E. Hunt et al., <u>Extended Abstracts</u> , Vol. 91-2, pp. 696-697, 1991					
	BF	"Epitaxial Layer Transfer by Bond and Etch Back of Porous Si", Takao Yonehara et al., <u>Applied Physics Letters</u> , Vol. 64, pp. 2108-2110, 1994					
Examiner				Date Considered			
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Examiner Initial		Patent Number	Publication Date	Name	Class	Sub-Class	Filing Date
	BG	6,221,740	4/24/01	Bryan et al.	438	458	
	BH	6,277,234 B1	8/21/01	Freund et al.	156	344	
	BI	6,321,134 B1	11/20/01	Henley et al.	700	121	11/20/01
	BJ	5,570,994	11/5/1996	Somekh et al.	414	786	5/10/1995
	BK	2,191,513	2/27/40	W. P. Bigelow	141	7	3/13/37
	BL	2,517,394	8/1/50	Z. U. Le Tellier	134	80	2/19/45
	BM	3,094,207	6/18/63	R. G. Millhiser et al.	198	209	5/24/61
	BN	3,489,608	1/13/70	B. Jacobs et al.	134	25	10/26/65
	BO	3,970,471	7/20/76	Bankes et al.	134	6	4/23/75
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Publication Date	Country	Class	Sub-Class	Translation
	BP	5-21338	1/29/93	Japan			English Abstract
	BQ	7-302889	11/14/95	Japan			English Abstract
	BR	WO 99/06110	02/11/99	WO			<input type="checkbox"/> Yes <input type="checkbox"/> No
	BS	WO 01/04933	01/18/01	WO			<input type="checkbox"/> Yes <input type="checkbox"/> No
	BT	WO 01/10644 A1	02/15/01	WO			<input type="checkbox"/> Yes <input type="checkbox"/> No
OTHER DOCUMENTS (Including Author, Title, Date, etc.)							
	BU	"Electrolytic Shaping of Germanium and Silicon", A. Uhlir et al., <u>Bell System Technical Journal</u> , Vol. 35, pp. 333-347, 1956					
	BV	"Oxidized Porous Silicon and It's Application", K. Nagano et al., <u>The Transactions of the Institute of Electronics and Communication Engineers, The Institute of Electronics, Information and Communication</u>					
	BW	"A New Dielectric Isolation Method Using Porous Silicon", K. Imai, <u>Solid -State Electronics</u> , Vol. 224, pp. 159-164, 1981					
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Examiner Initial		Patent Number	Publication Date	Name	Class	Sub-Class	Filing Date
	BX	4,047,973	9/13/77	Williams	134	10	10/27/76
	BY	4,208,760	6/24/80	Dexter et al.	15	302	12/19/77
	BZ	4,215,928	8/5/80	Bayley et al.	354	319	3/30/79
	CA	4,850,381	7/25/89	Moe et al.	134	62	2/1/88
	CB	5,248,886	9/28/93	Asakawa et al.	250	442.11	2/27/92
	CC	5,357,645	10/25/94	Onodera	15	97.1	5/14/93
	CD	5,653,247	8/5/1997	Murakami	134	80	8/14/95
	CE	5,679,405	10/21/97	Thomas et al.	427	248.1	7/24/95
	CF	5,792,709	8/11/98	Robinson et al.	438	692	12/19/95
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Patent Number	Publication Date	Country	Class	Sub-Class	Translation
	CG	JPA 56-30650	3/27/81	Japan			Abstract Only
	CH	JPA60-05530	1/14/94	Japan			English Abstract
	CI	JPA4-293236	10/16/92	Japan			English Abstract
OTHER DOCUMENTS (Including Author, Title, Date, etc.)							
	CJ	"Silicon on Insulator Material by Wafer Bonding", Christine Harendt, Charles E. Hunt et al., <i>Journal of Electronic Materials</i> , vol. 20, pp. 267-277, 1991					
	CK	Michel Bruel, et al. "Smart-Cut: A New Silicon On Insulator Material Technology Based On Hydrogen Implantation And Wafer Bonding", Jpn. J. Appl. Phys. Vol. 36, No. 3B, Part 01, March 1, 1997, pages 1636-1641.					
	CL	U.S. Application Serial No. 09/399,643, filed September 20, 2002, entitled "Separating Apparatus and Method, and Substrate Manufacturing Method."					
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	CM	5,795,401	8/18/98	Itoh et al.	134	6	10/10/96
	CN	5,810,028	9/22/98	Ichikawa et al.	134	66	6/12/97
	CO	5,820,329	10/13/98	Derbinski et al.	414	225	4/10/97
	CP	5,954,888	9/21/99	Gupta et al.	134	3	2/9/98
	CQ	6,007,675	12/28/99	Toshima	156	345	12/1/97
	CR	6,168,499	1/2/2001	Jang	451	8	5/18/99
	CS	4,915,564	4/10/90	Erer et al.	414	217	7/20/98
	CT	6,131,589	10/17/00	Vogtmann et al.	134	113	2/9/99
	CU	6,382,292	5/7/02	Ohmi et al.	156	584	3/25/98
	CV	6,418,999	7/16/02	Yanagita et al.	156	584	12/15/98
	CW	6,527,031	3/4/03	Yanagita et al	156	584	11/5/99
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Patent Number	Publication Date	Country	Class	Sub-Class	Translation
	CX	JPA63-16455	11/15/94	Japan			English Abstract
	CY	JPA9-167724	6/24/97	Japan			English Abstract
	CZ						<input type="checkbox"/> Yes <input type="checkbox"/> No
OTHER DOCUMENTS (Including Author, Title, Date, etc.)							
	DA	U.S. Application Serial No. 09/434,740, filed November 11, 2002, entitled "Sample Separating Apparatus and Method."					
	DB	U.S Application No. 09/434,663, filed November 5, 1999, entitled "Sample Processing System," to K. Yanagita et al.					
	DC	"History of Water Jet Machining Development", Journal of the Water Jet Technology Society of Japan, vol. 1, No. 1, 1984, pages 4-15.					
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